IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Akiyoshi SUZUKI et al.	: Previous Examiner: F. Braun
rangoshi 5020tti et ui.) : Previous Group Art Unit: 2852
Application No.: Divisional of Appln. No. 09/810,488, filed March 19, 2001) :
Filed: October 17, 2003) :)
For: EXPOSURE APPARATUS AND DEVICE	October 17, 2003
MANUFACTURING METHOD INCLUDING)
CHANGING A PHOTO-INTENSITY DISTRIBUTION OF A LIGHT SOURCE AND	; }
ADJUSTING AN ILLUMINANCE	, :
DISTRIBUTION ON A SUBSTRATE IN)
ACCORDANCE WITH THE CHANGE	•
(As Amended))

Mail Stop Patent Application Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the document listed on the enclosed PTO-1449 form. Copies of the listed documents are also enclosed.

These documents were cited during prosecution of copending parent application no.

09/810,488, filed March 19, 2001.

Applicants request that the above information be considered by the Examiner and

that a copy of the enclosed PTO-1449 form be initialed and returned indicating that such

information has been considered.

This Information Disclosure Statement is being filed before the issuance of a first

Office Action on the merits. Therefore, no fee under 37 C.F.R. 1.97(c)(2) is believed due.

Nevertheless, the Commissioner may charge Deposit Account No. 06-1205, should any fee

be due for filing this paper.

Applicants' undersigned attorney may be reached in our Washington D.C. office

by telephone at (202) 530-1010. All correspondence should continue to be directed to our

address given below.

Respectfully submitted,

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SEW/eab

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FORM PTO 1449 (modified) ATTY DOCKET NO. 00684.00152.13 APPLICATION NO. Divisional of Appln. No. 09/819,488, filed U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE March 19, 2001 LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary) APPLICANT Akiyoshi SUZUKI et al. October 17, 2003 FILING DATE October 17, 2003 **GROUP 2852** U.S. PATENT DOCUMENTS *EXAMINER INITIAL DOCUMENT NUMBER FILING DATE IF APPROPRIATE DATE NAME CLASS **SUBCLASS** US-3,729,252 04/24/1973 Nelson 350 162 SF US-3,776,633 12/04/1973 Frosch et al. 355 132 US-3,887,816 06/03/1975 350 Colley 571 01/29/1985 Konno et al. US-4,497,015 362 268 02/12/1985 US-4,498,742 **Uehara** 350 523 06/04/1985 350 US-4,521,082 Suzuki et al. 405 US-4.619.508 10/28/1986 Shibuya et al. 353 122 US-4,634,240 01/06/1987 Suzuki et al. 350 508 FOREIGN PATENT DOCUMENTS TRANSLATION DOCUMENT NUMBER DATE COUNTRY CLASS SUBCLASS YES/NO/ OR ABSTRACT 61-91662 05/09/1986 Japan Abstract 0 346 844 06/13/1989 Europe 0 293 643 05/10/1988 Europe 0 437 376 01/11/1991 Europe 0 486 316 11/15/1991 Europe OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.) Pol, Victor, et al. "Excimer Laser Based Lithography: A Deep-Ultraviolet Wafer Stepper for VLSI Processing," Optical Engineering, Vol. 26, No. 4, pp. 311-318, April 1987. Yang, S.T., et al. "Effect of Central Obscuration on Image Formation in Projection Lithography," SPIE Vol. 1264 Optical/Laser Microlithography III, pp. 477-485, 1990. H cht-Zajac, Optics, 1st Edition, p. 117, 1974. **EXAMINER** DATE CONSIDERED

^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

FORM PTO 1449 (modified) ATTY DOCKET NO. 00684.00152.13 APPLICATION NO. Divisional of U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE Appln. No. 09/819,488, filed March 19, 2001 LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary) APPLICANT Akiyoshi SUZUKI et al. October 17, 2003 **GROUP 2852** FILING DATE October 17, 2003 U.S. PATENT DOCUMENTS *EXAMINER INITIAL DOCUMENT FILING DATE DATE CLASS SUBCLASS NAME NUMBER US-4,645,924 02/24/1987 Suzuki et al. 250 236 05/26/1987 US-4.668.077 Tanaka 355 30 Suzuki et al. US-4,780,747 10/25/1988 355 68 US-4,851,882 07/25/1989 Takahashi et al. 355 46 US-4,924,257 05/08/1990 Jain 355 53 US-4,931,830 06/05/1990 Suwa et al. 355 71 US-4,947,030 08/07/1990 Takahashi 250 201.1 01/29/1991 US-4,988,188 Ohta 353 122 FOREIGN PATENT DOCUMENTS TRANSLATION YES/NO/ OR ABSTRACT DOCUMENT NUMBER DATE COUNTRY CLASS **SUBCLASS** 39 33 308 A1 05/03/1990 Germany No 28 35 363 A1 03/13/1980 Germany No 40 07 069 A1 09/20/1990 Germany No 61-210627 09/18/1986 Abstract Japan OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.) Intl. Cl., 5th Edition, Vol. 7, Section G, pp. 68 and 72, 1989. Glatzel, Erhard. "New Lenses for Microlithography," SPIE, Vol. 237, p. 310, International Lens Design Conference (OSA), 1980. European Search Report regarding 01200962.7 dated May 31, 2001. Europ an S arch R port r garding 97200014.5 dated May 20, 1997. **EXAMINER** DATE CONSIDERED

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